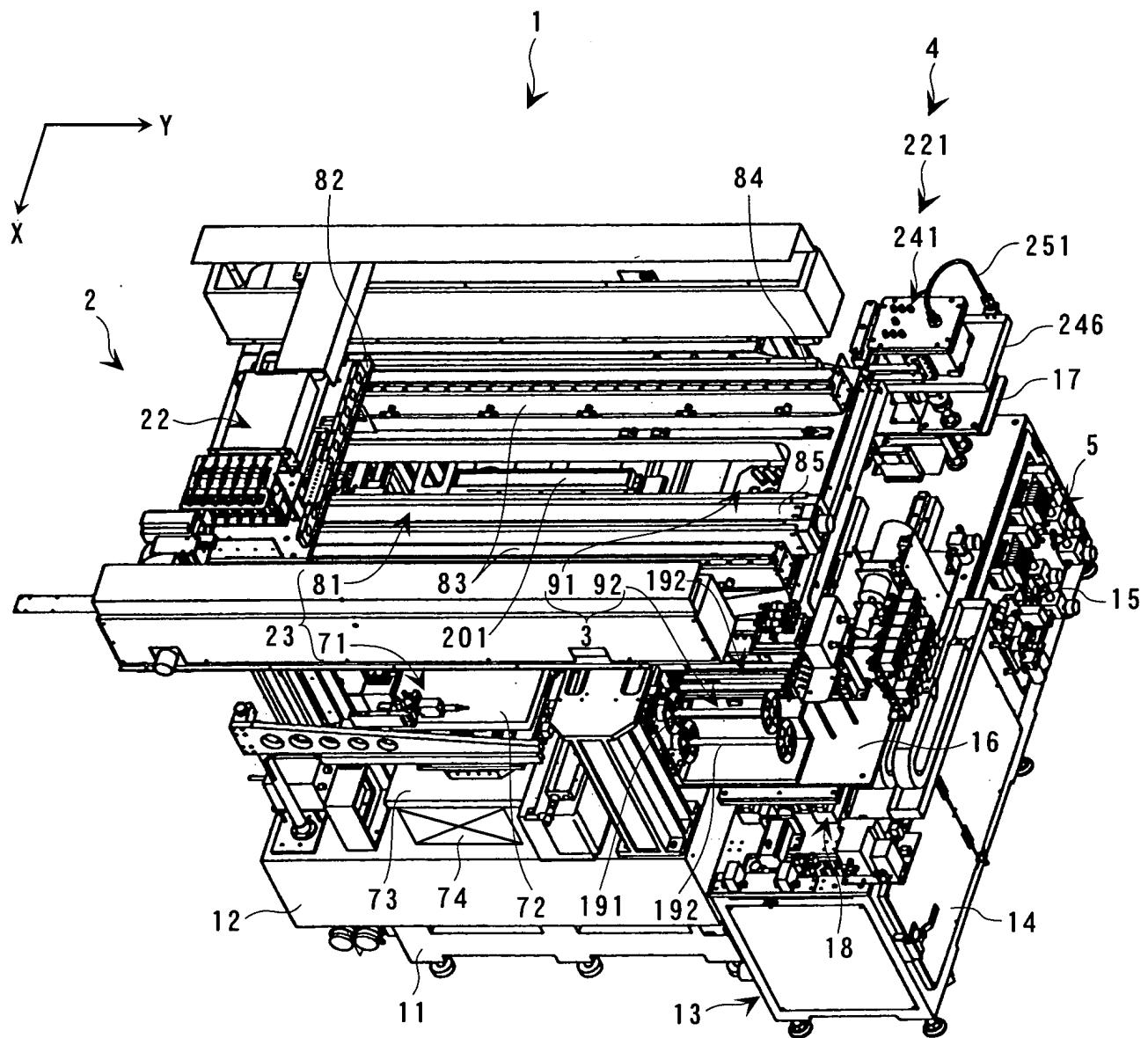


FIG. 1

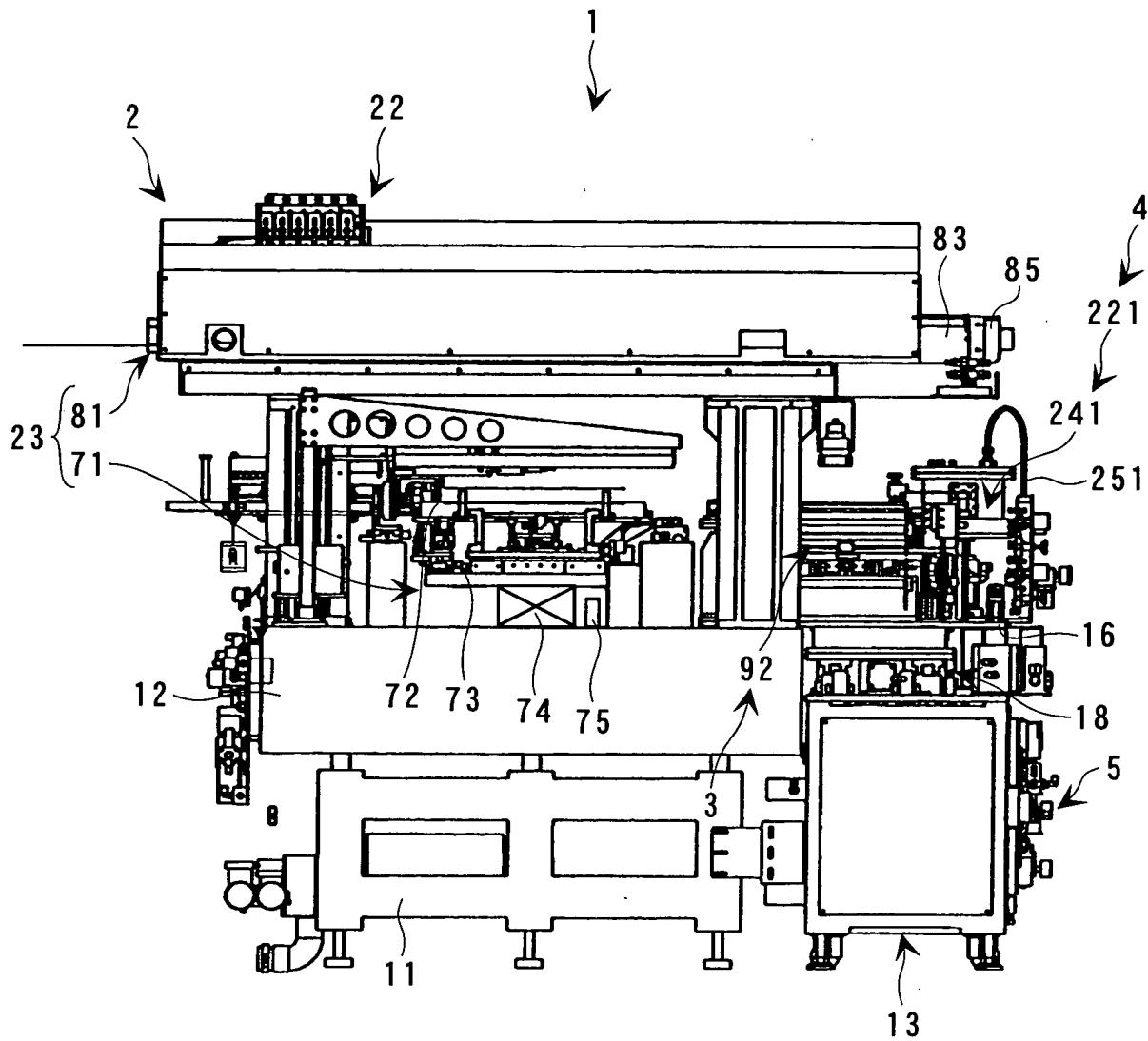


Title: METHOD OF DETERMINING ABNORMALITY OF NOZZLES IN IMAGING APPARATUS;
IMAGING APPARATUS; ELECTROOPTIC DEVICE; METHOD OF MANUFACTURING
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F I G. 2



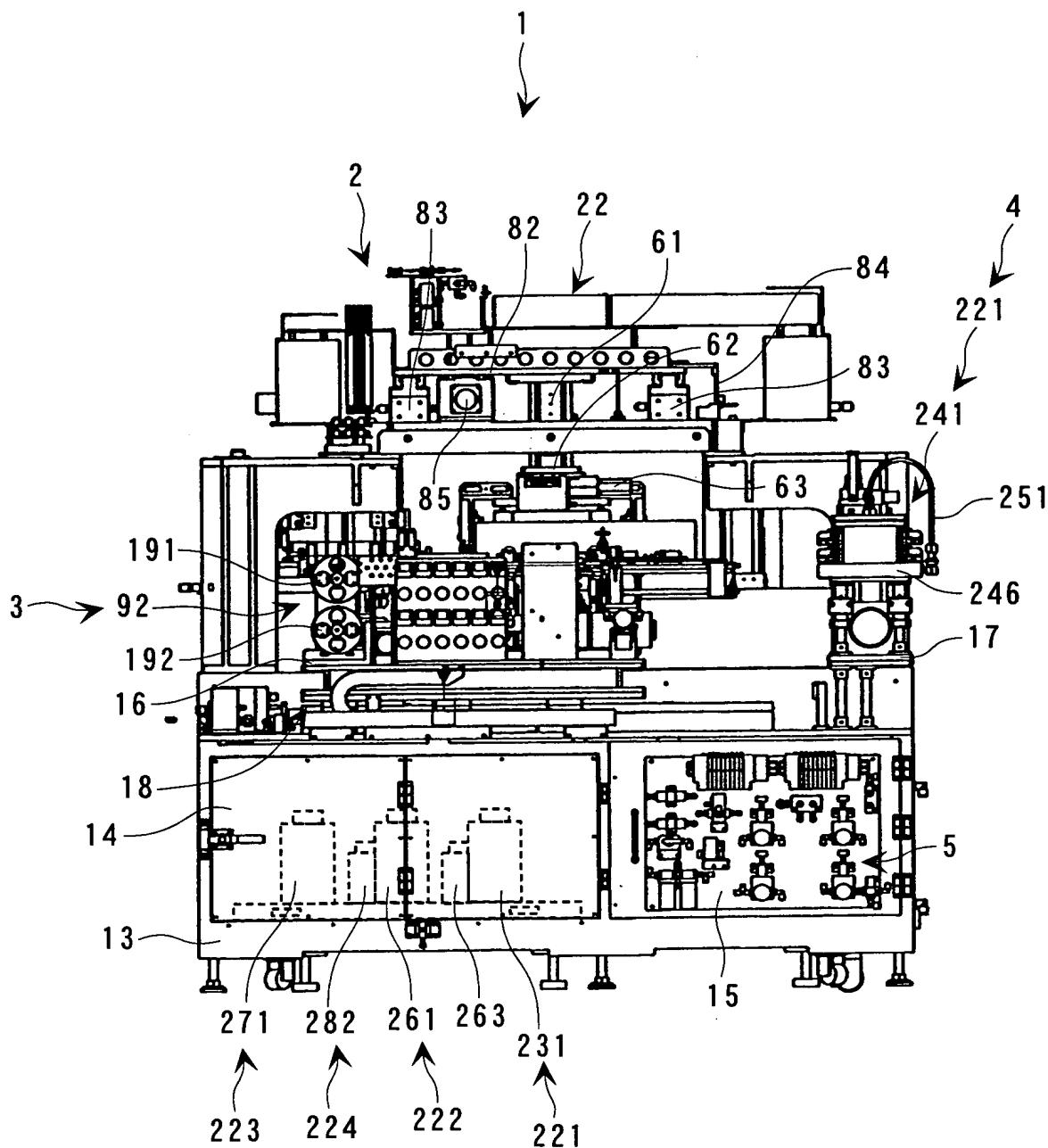
Title: METHOD OF DETERMINING ABNORMALITY OF NOZZLES IN IMAGING APPARATUS;
IMAGING APPARATUS; ELECTROOPTIC DEVICE; METHOD OF MANUFACTURING
ELECTROOPTIC DEVICE; AND ELECTRONIC EQUIPMENT

Inventor: Shinichi NAKAMURA

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F I G. 3



F I G. 4

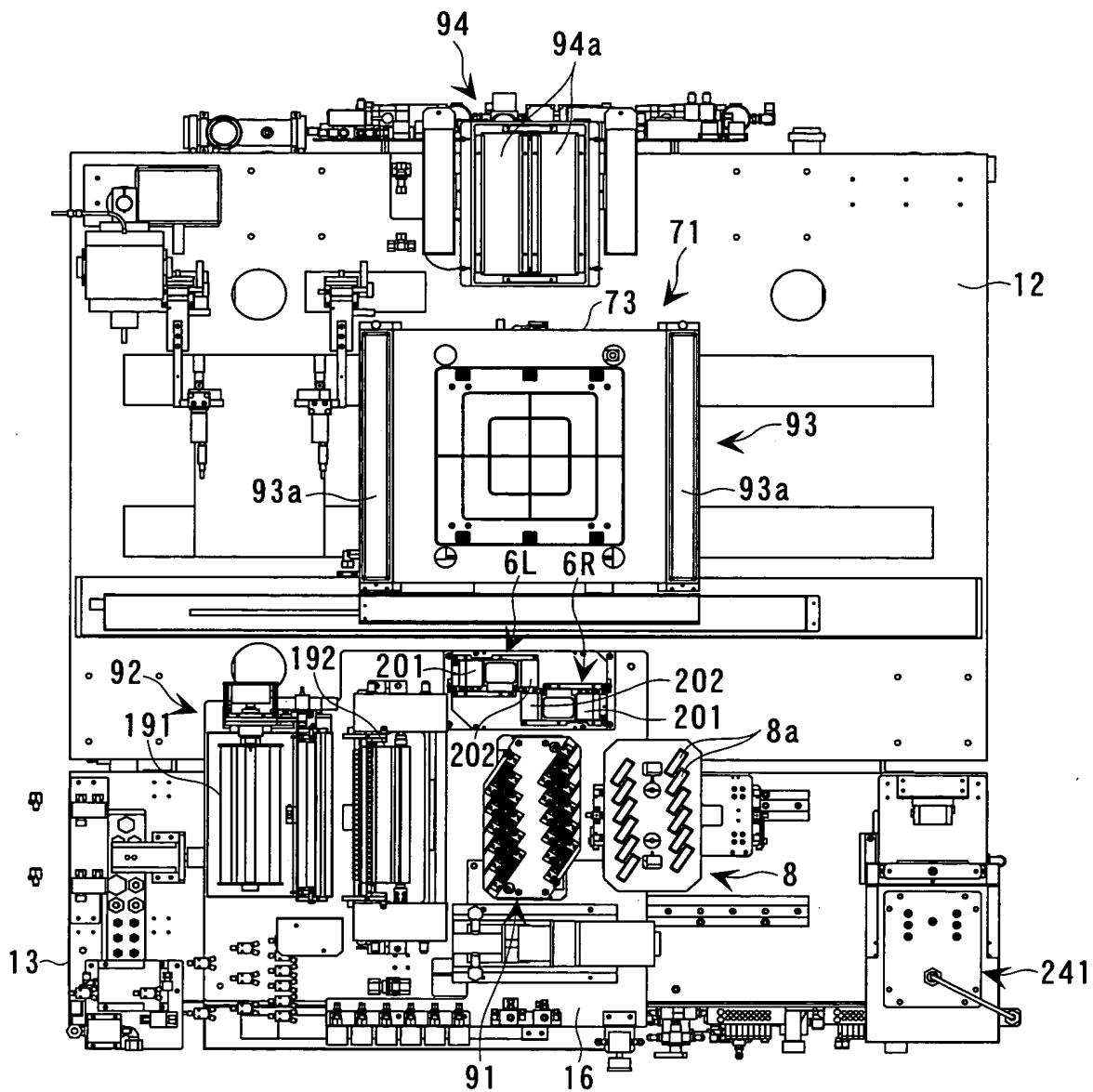
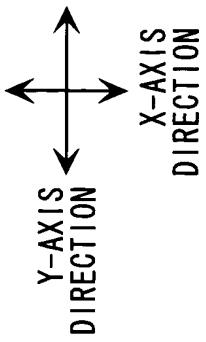
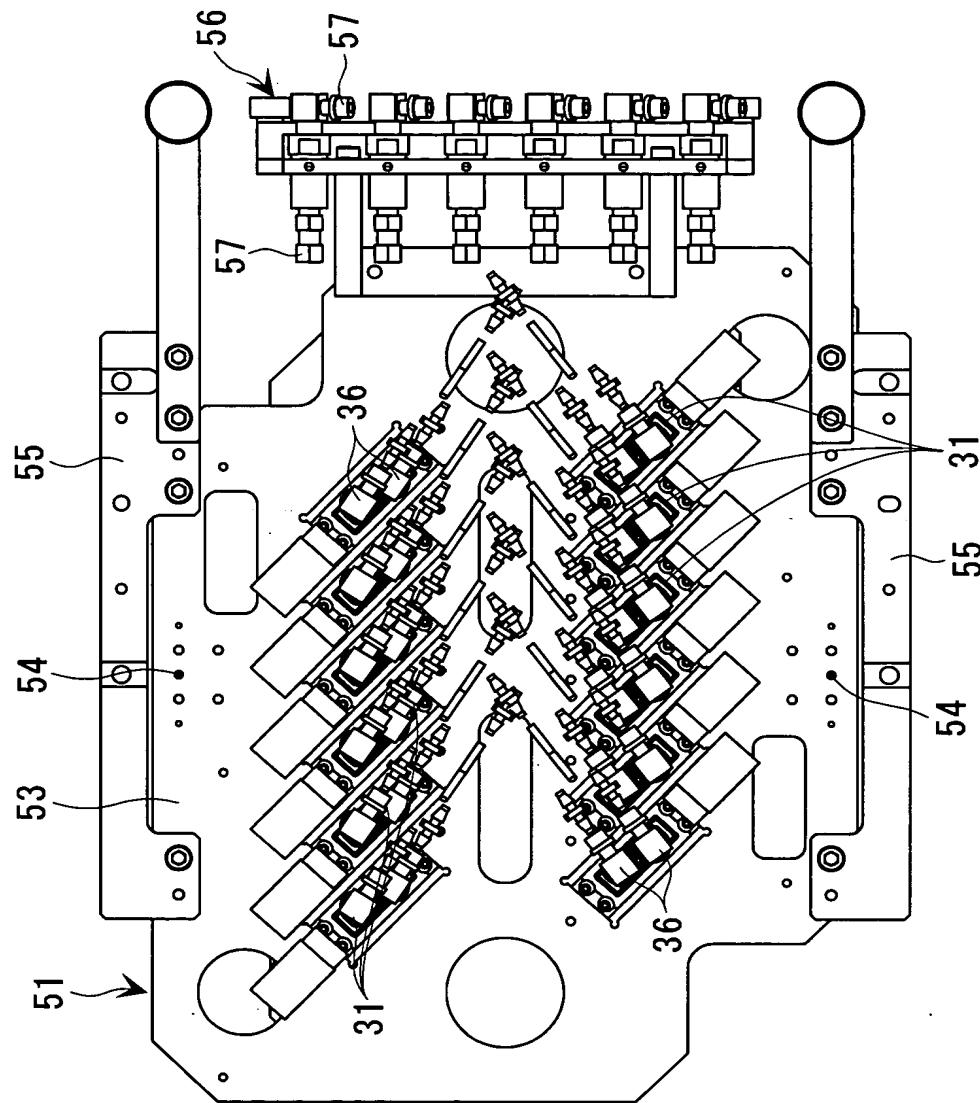


FIG. 5
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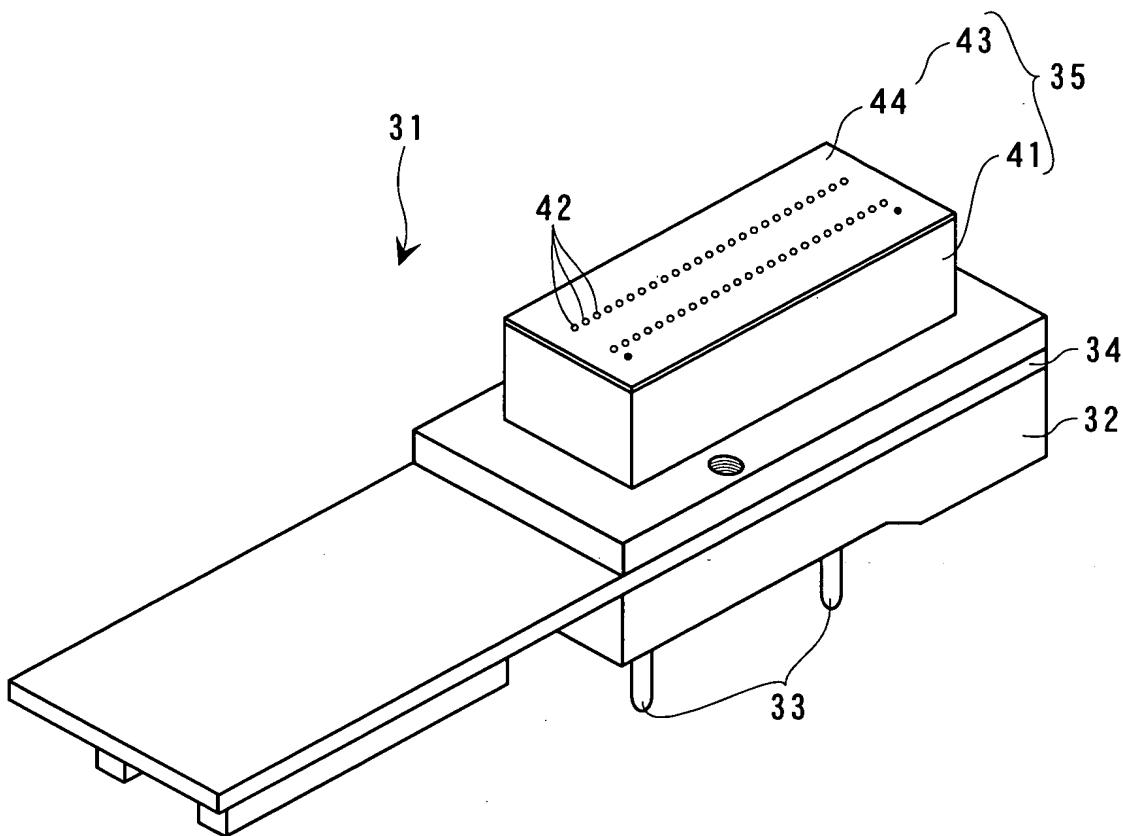


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ELECTROOPTIC DEVICE; AND ELECTRONIC EQUIPMENT

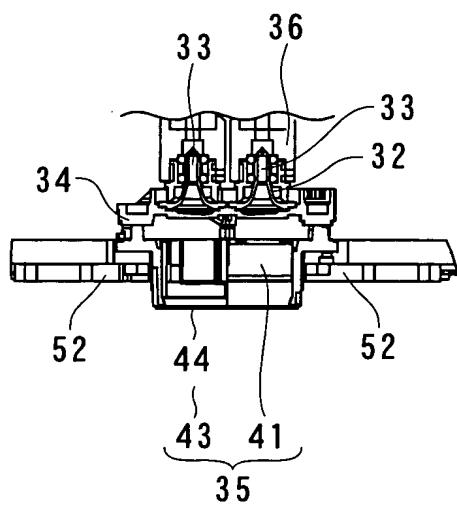
Inventor: Shinichi NAKAMURA
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F I G. 6 A



F I G. 6 B

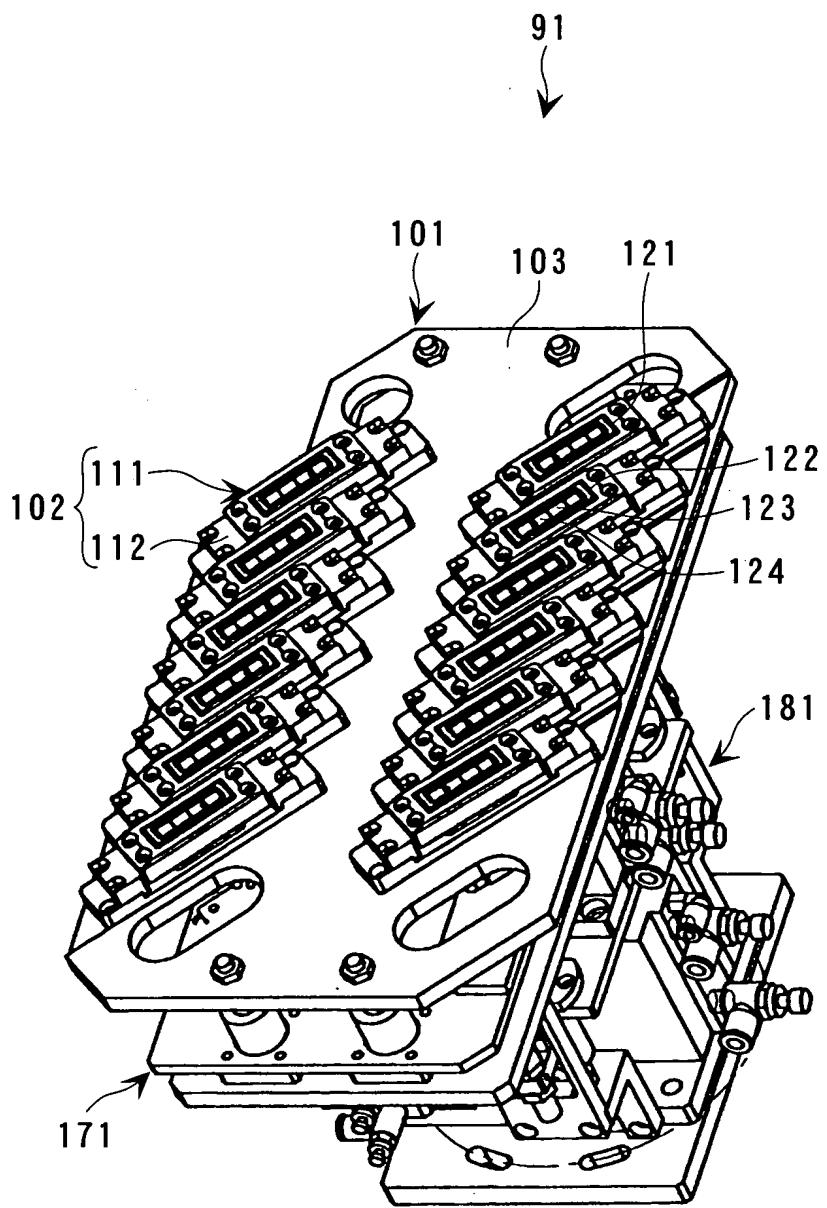


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IMAGING APPARATUS; ELECTROOPTIC DEVICE; METHOD OF MANUFACTURING
ELECTROOPTIC DEVICE; AND ELECTRONIC EQUIPMENT

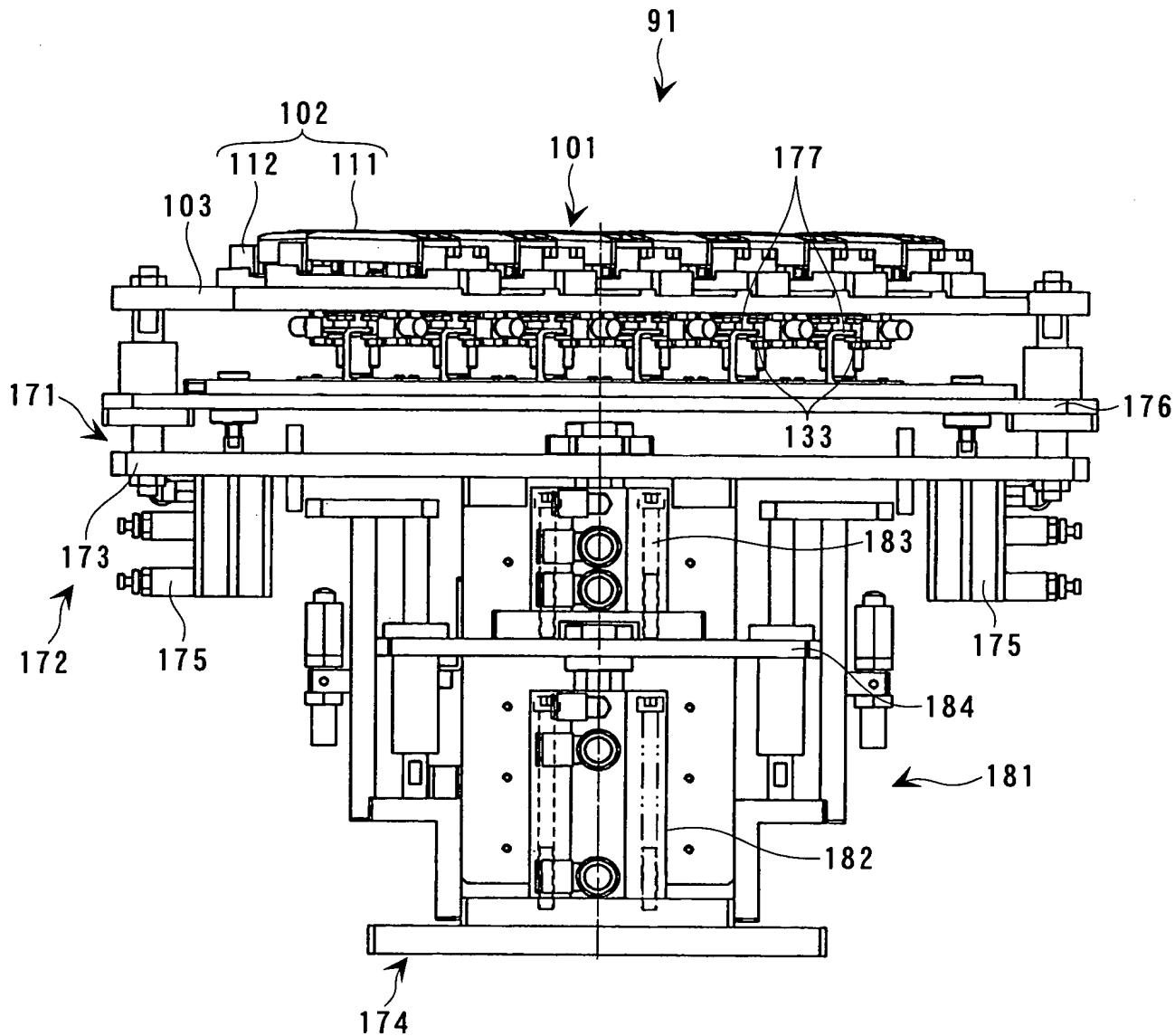
Inventor: Shinichi NAKAMURA
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F I G. 7



F I G. 8

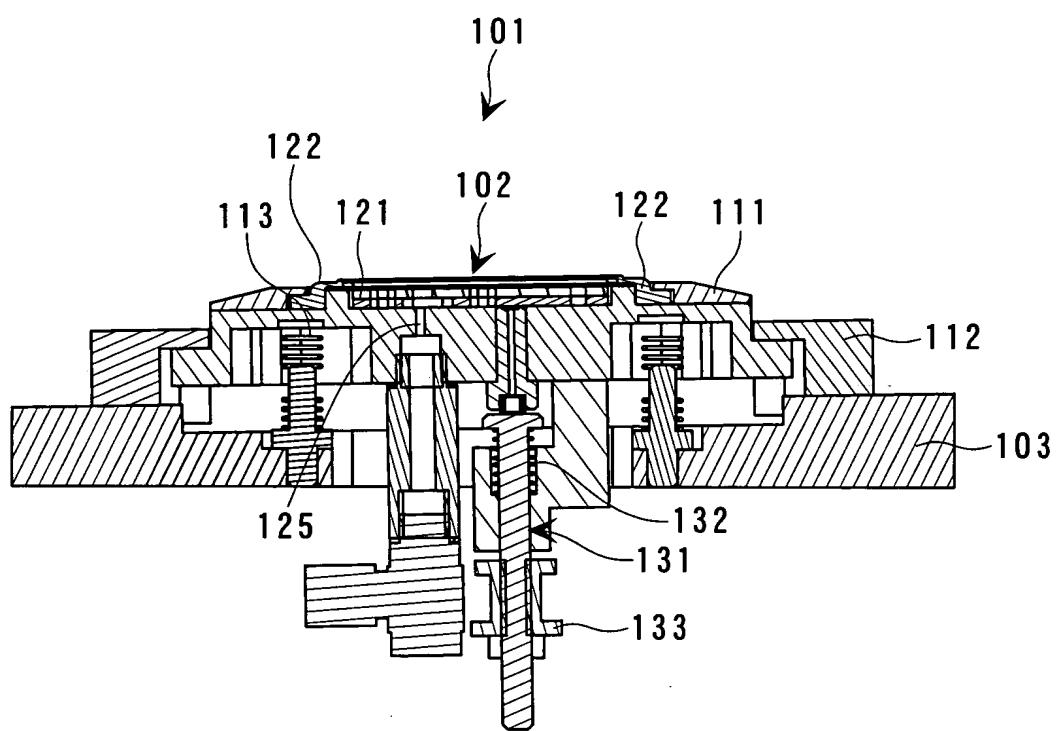


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IMAGING APPARATUS; ELECTROOPTIC DEVICE; METHOD OF MANUFACTURING
ELECTROOPTIC DEVICE; AND ELECTRONIC EQUIPMENT

Inventor: Shinichi NAKAMURA
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F I G. 9

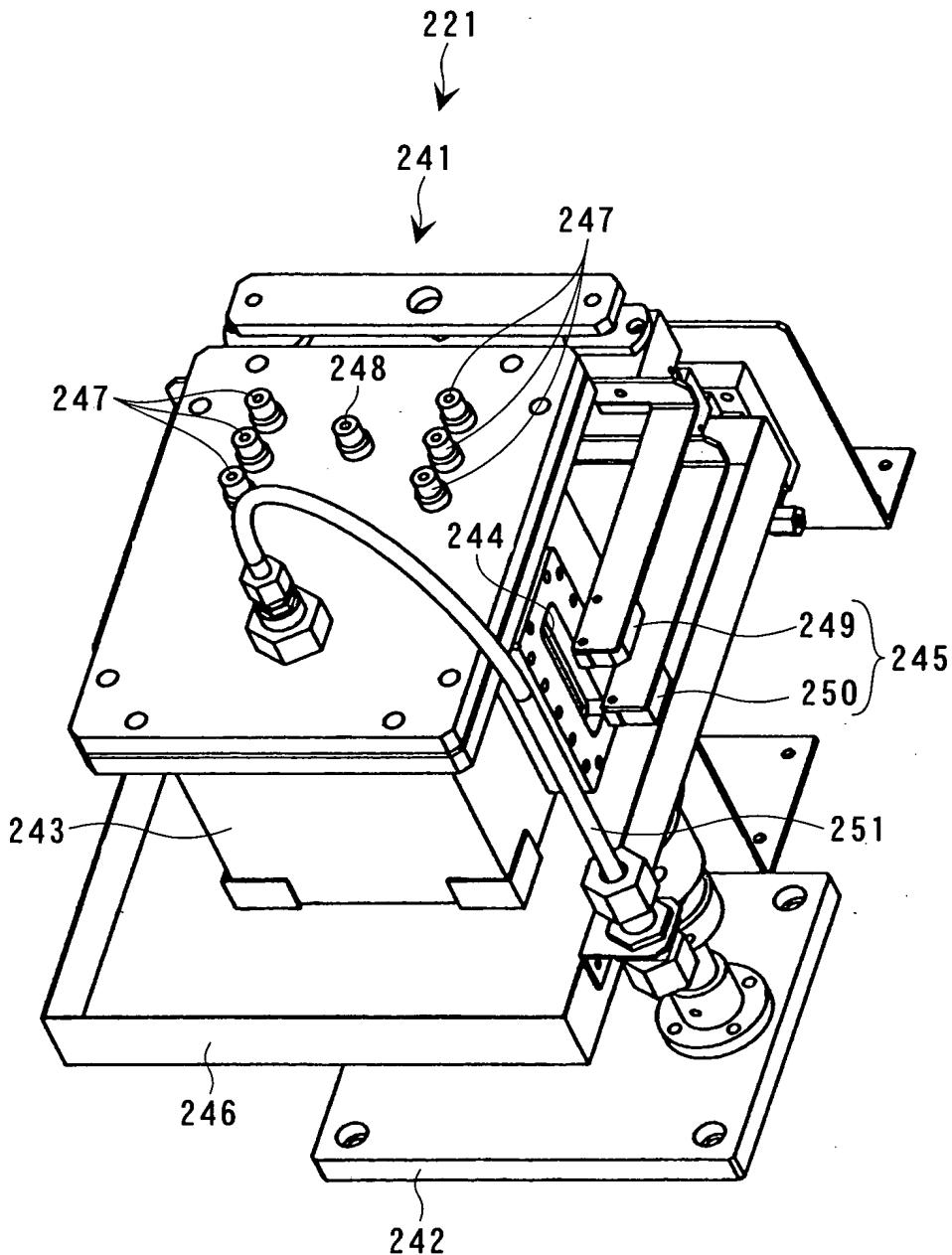


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ELECTROOPTIC DEVICE; AND ELECTRONIC EQUIPMENT

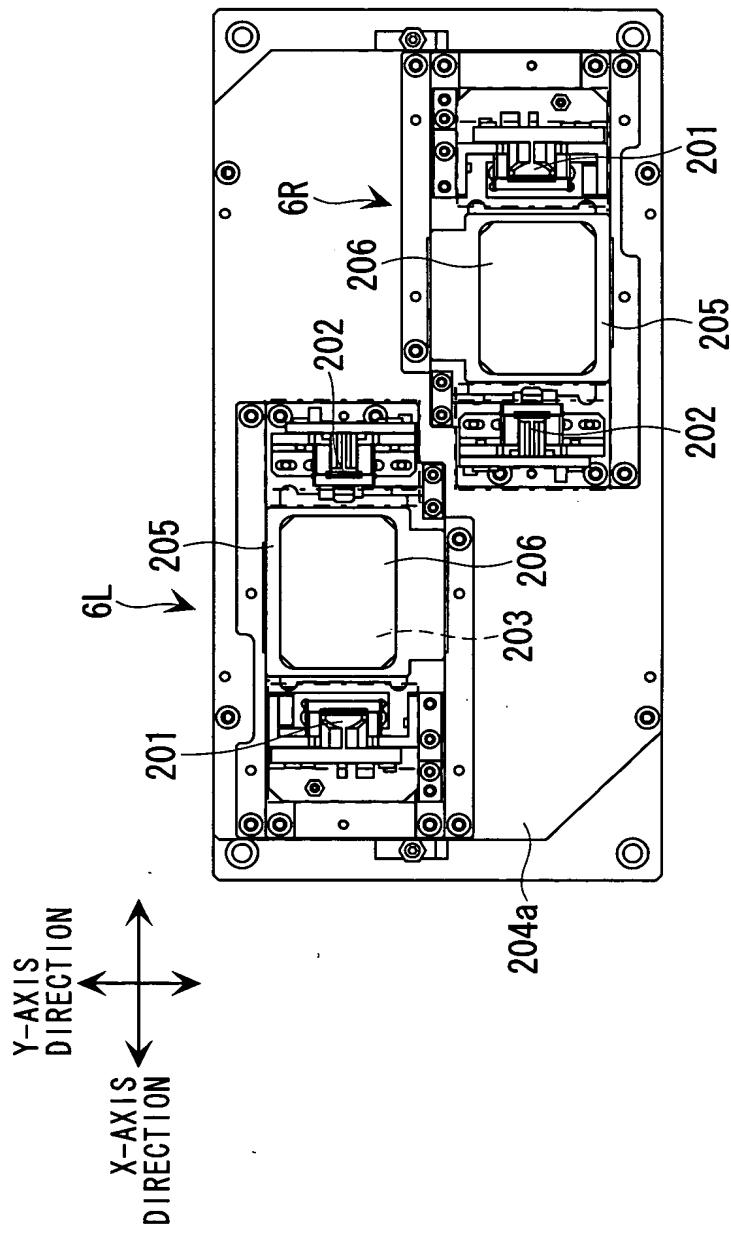
Inventor: Shinichi NAKAMURA
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F I G. 10

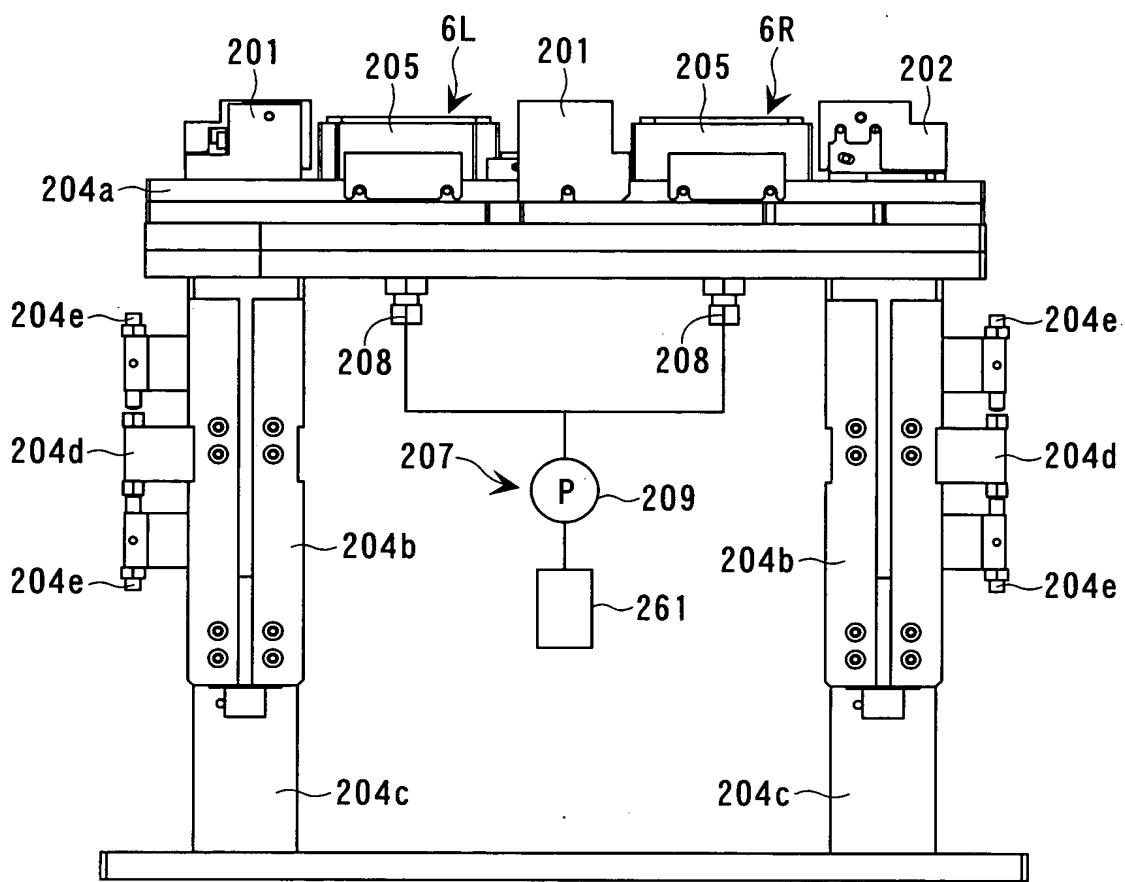


F I G. 11



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F I G. 1 2



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Inventor: Shinichi NAKAMURA
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F I G. 1 3

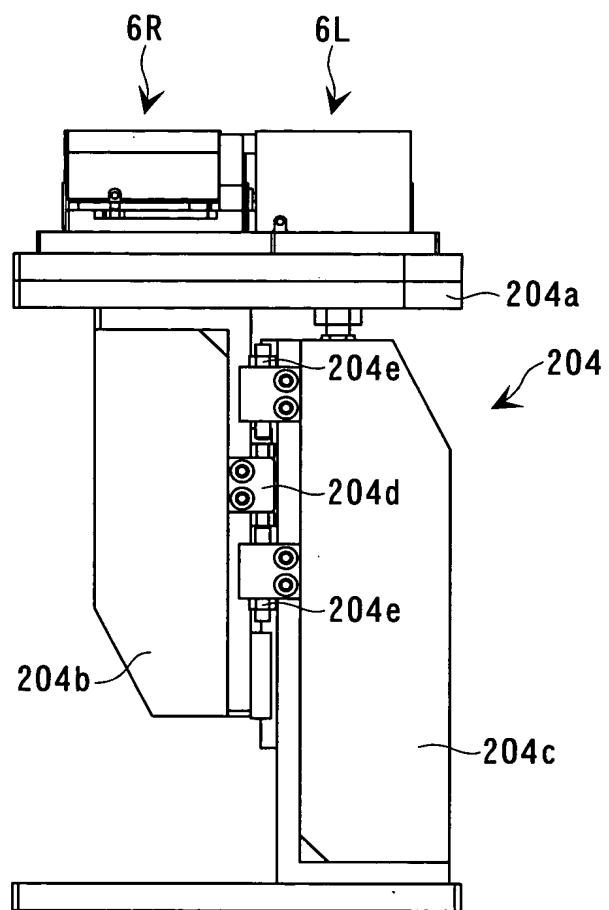


FIG. 14

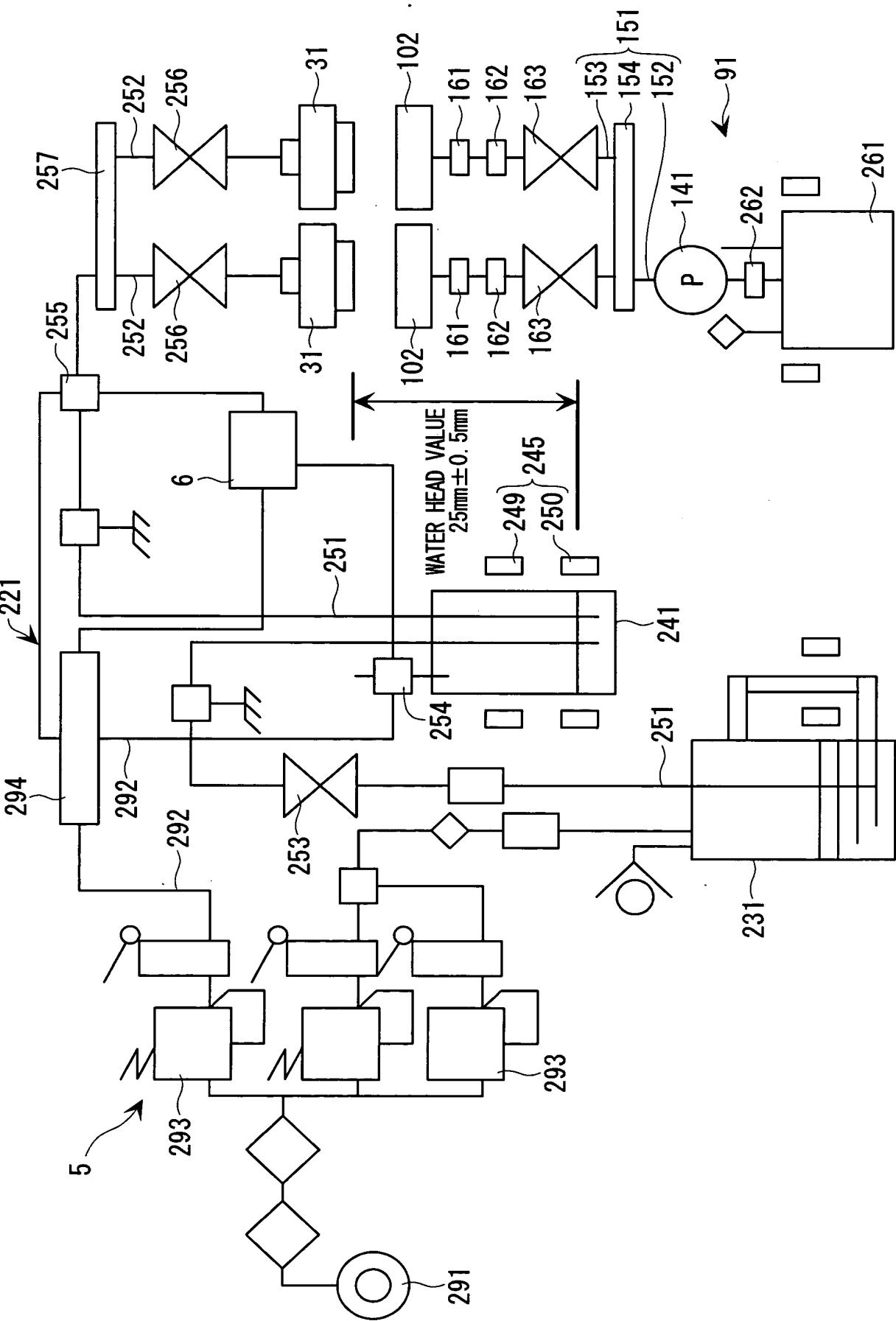
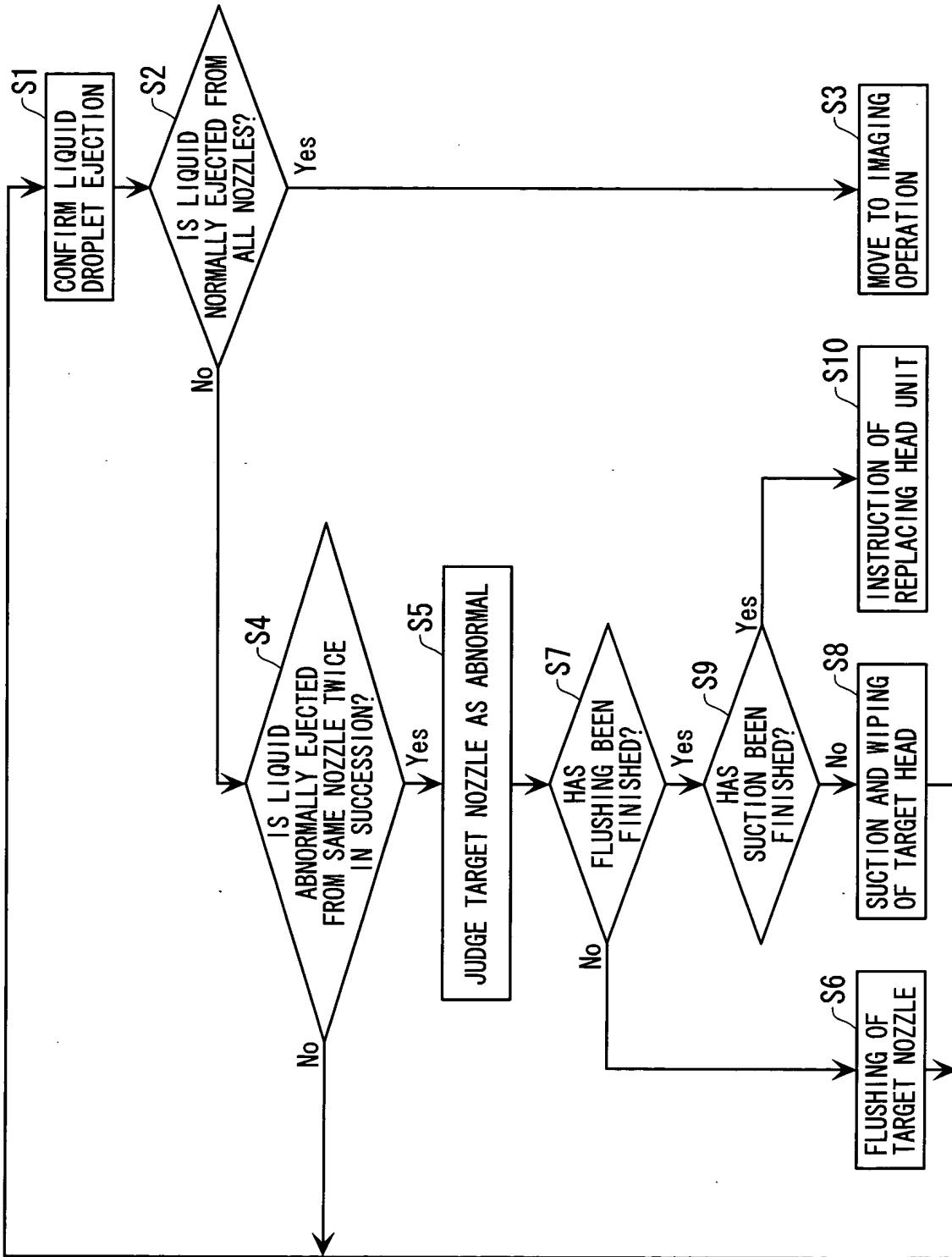
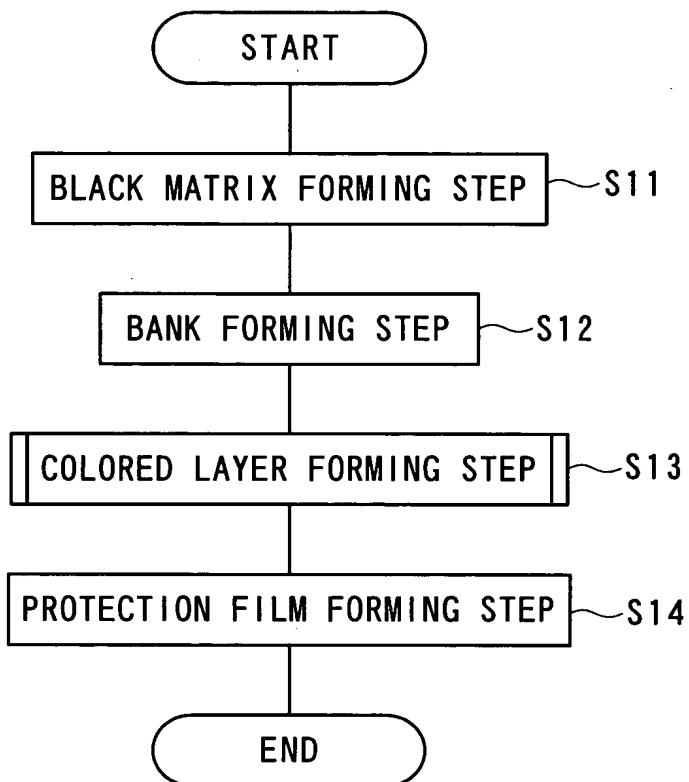


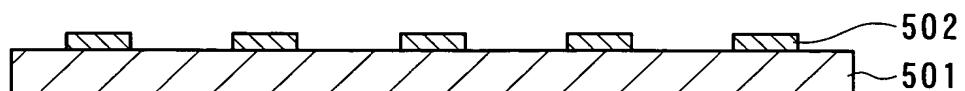
FIG. 15



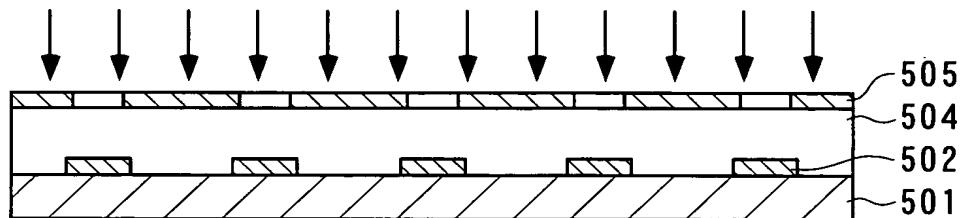
F I G. 1 6



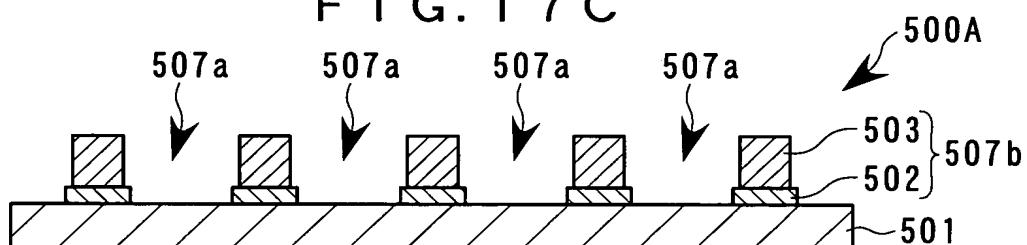
F I G. 17 A



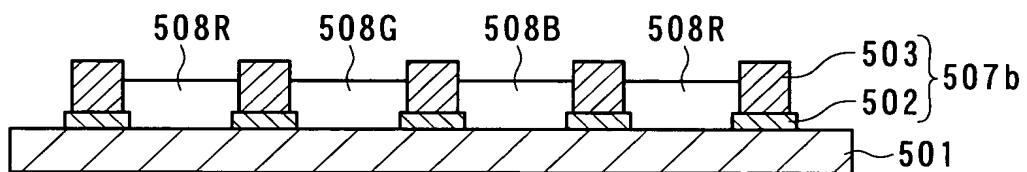
F I G. 17 B



F I G. 17 C



F I G. 17 D



F I G. 17 E

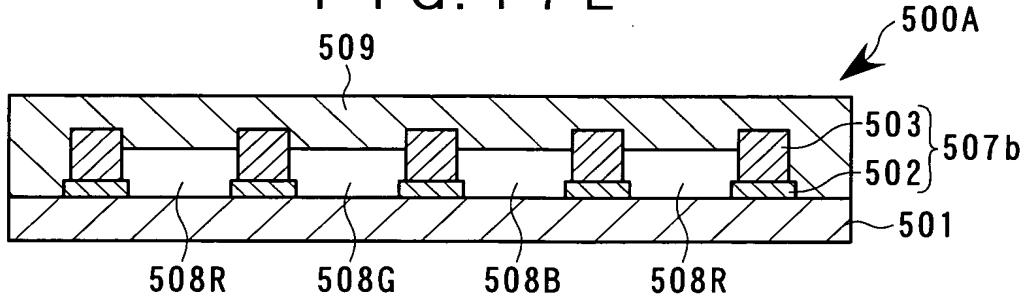


FIG. 18

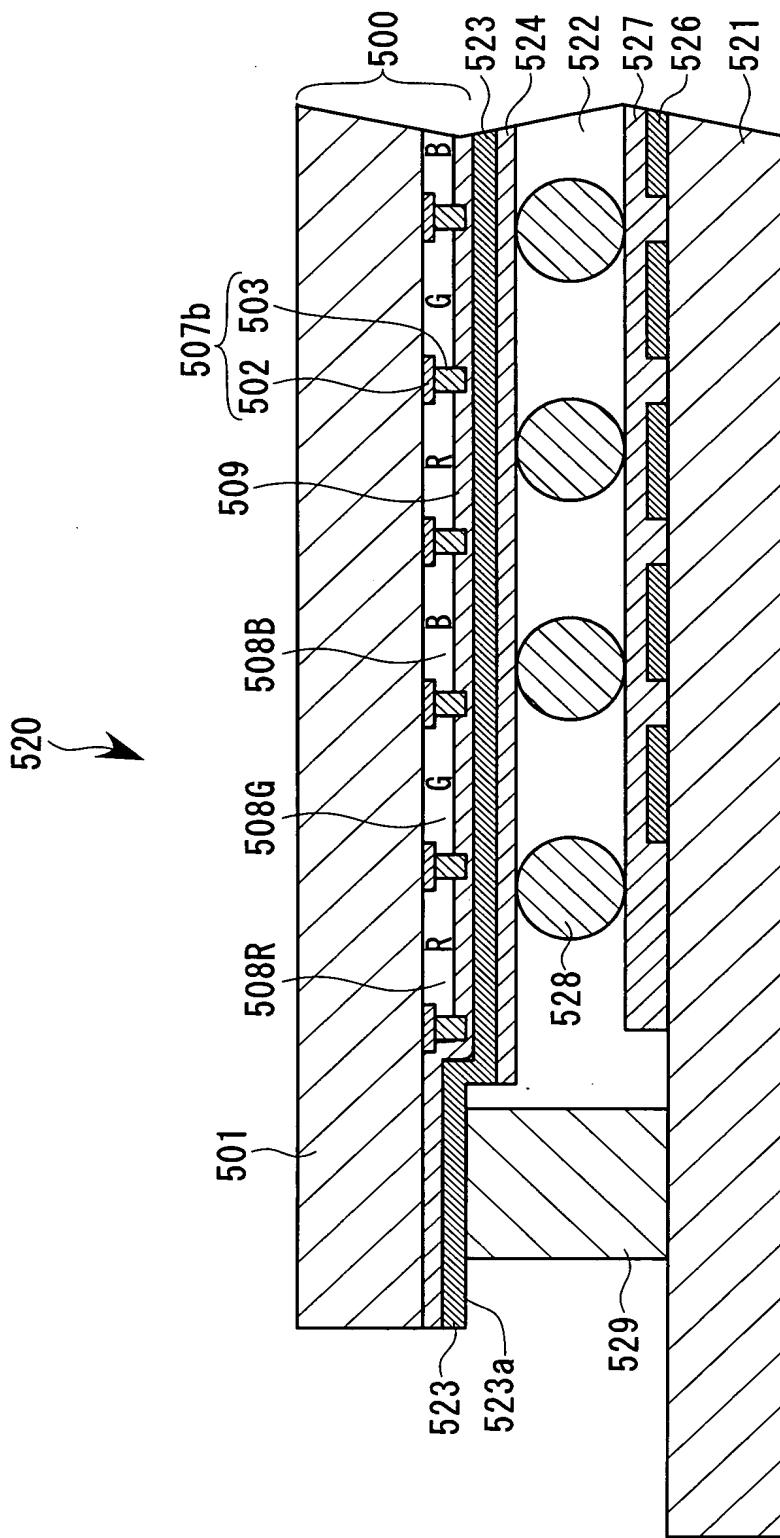
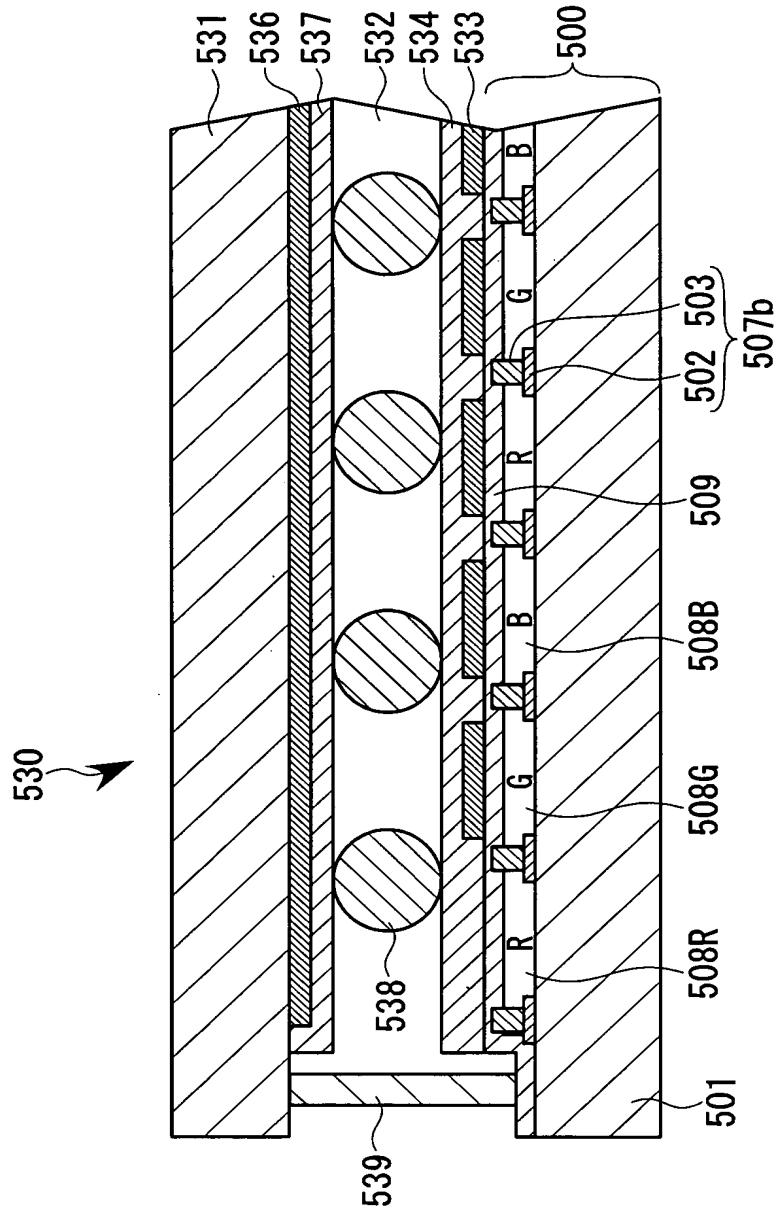
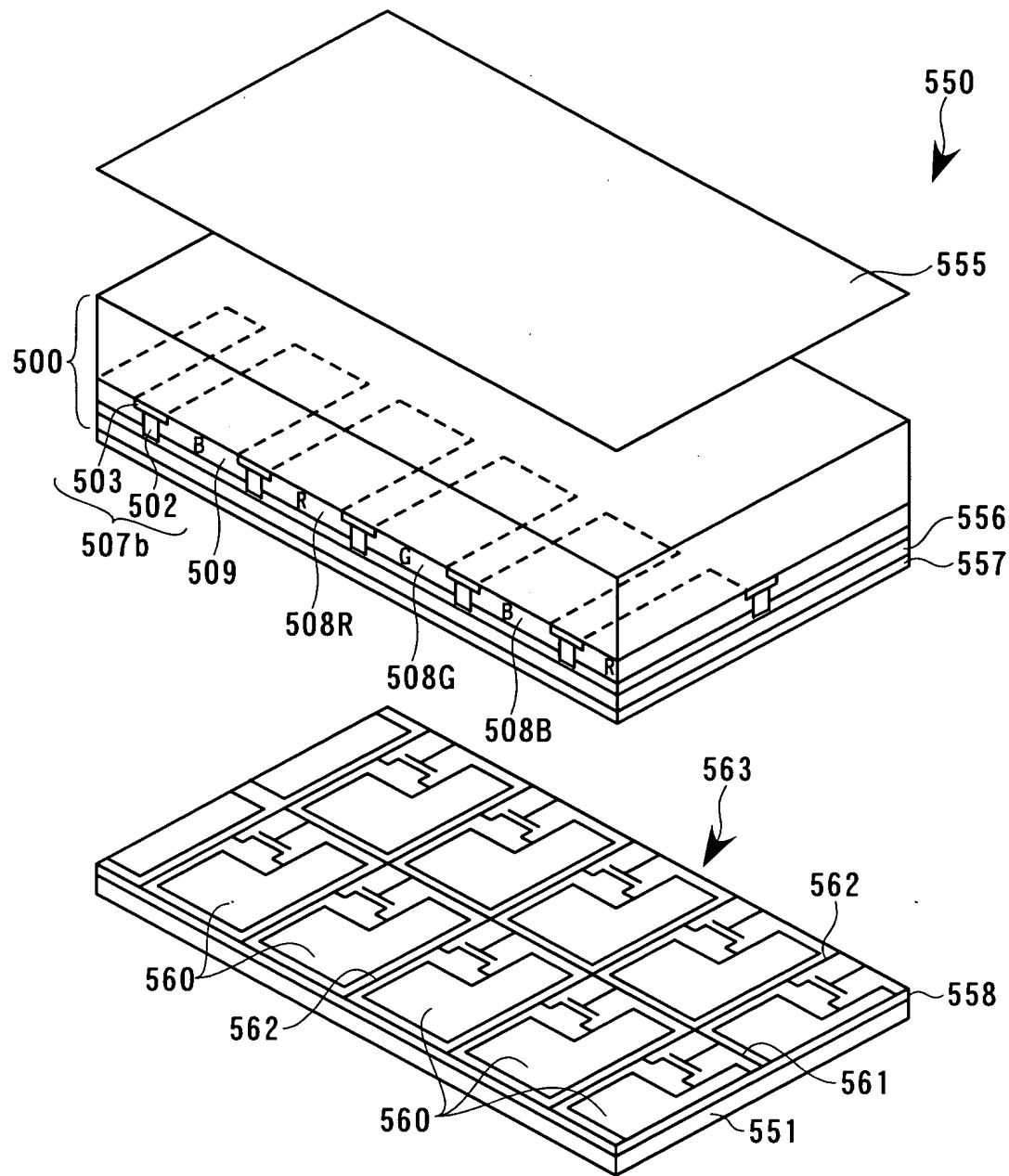


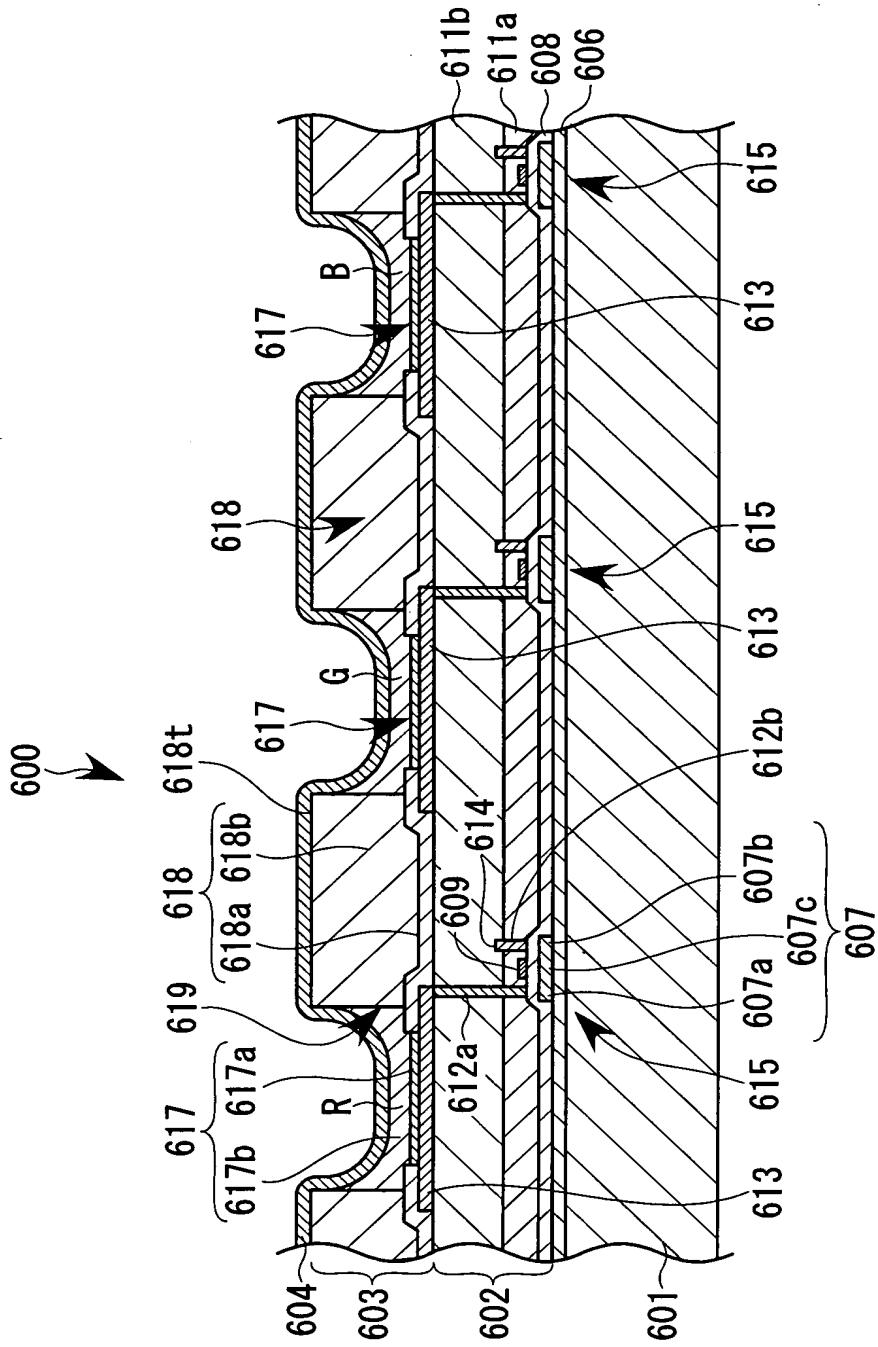
FIG. 19



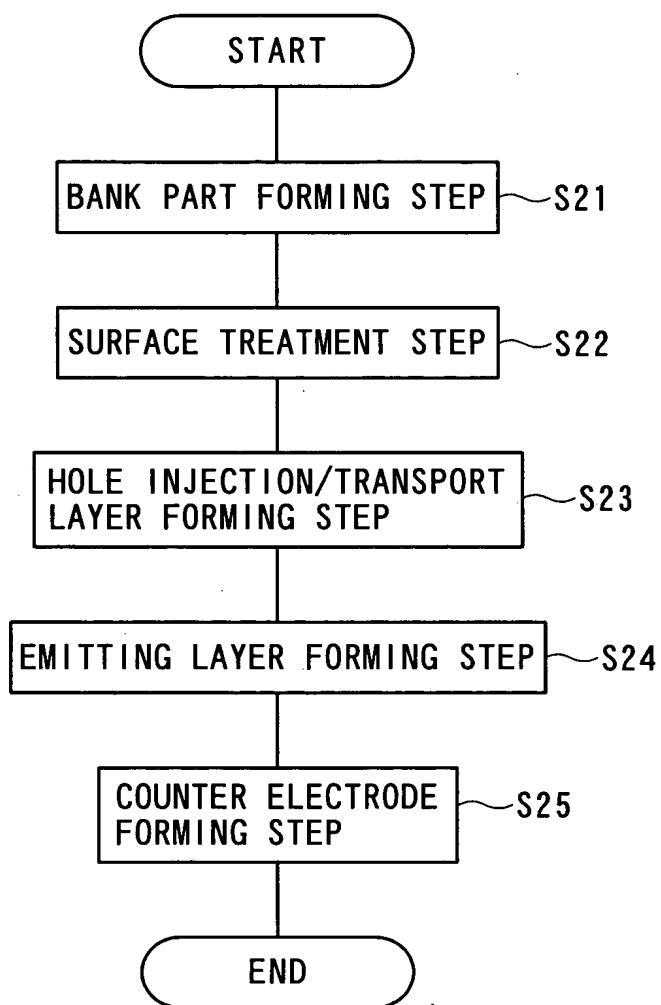
F I G. 20



F I G. 21



F I G. 2 2



F I G. 2 3

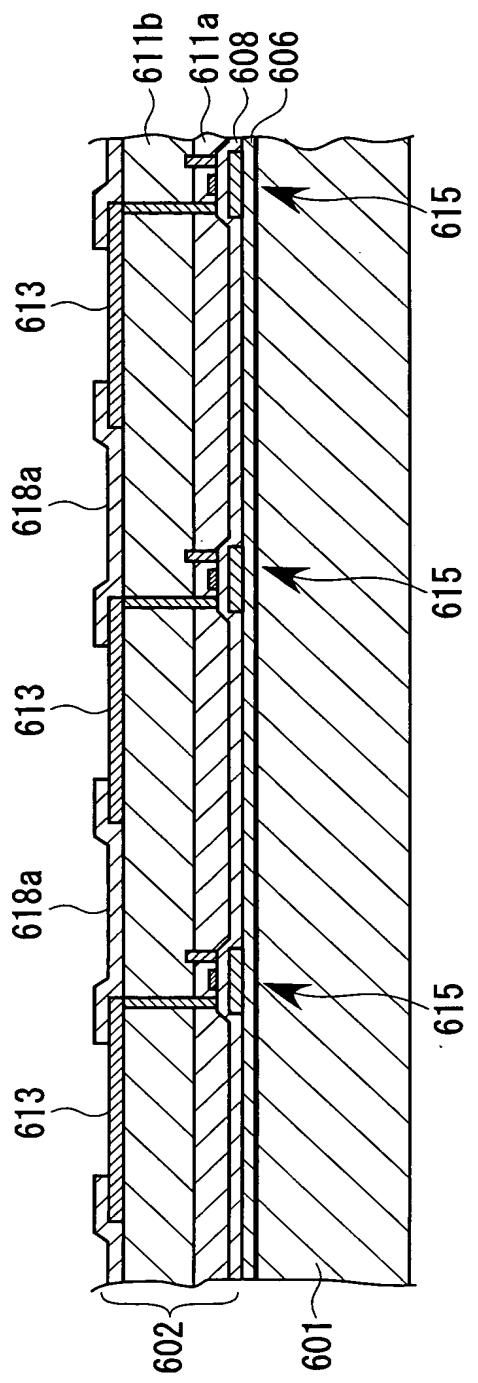


FIG. 24

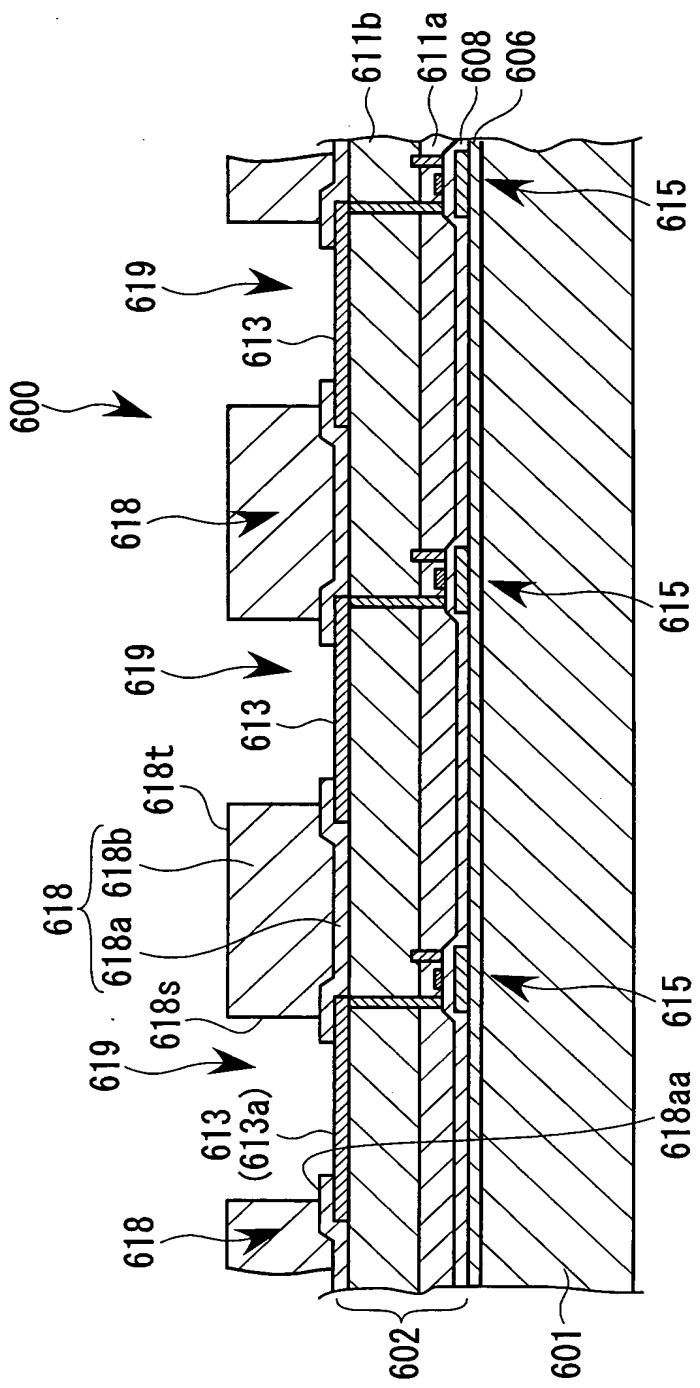


FIG. 25

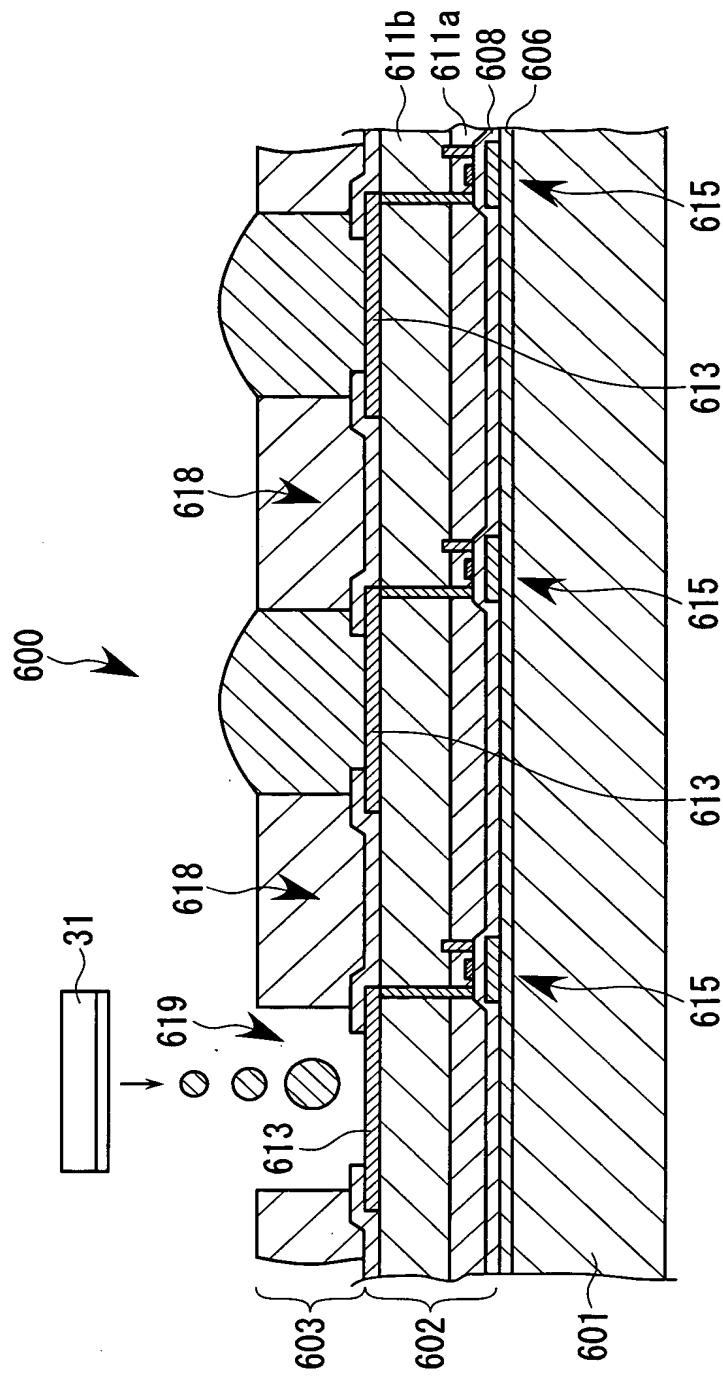


FIG. 26

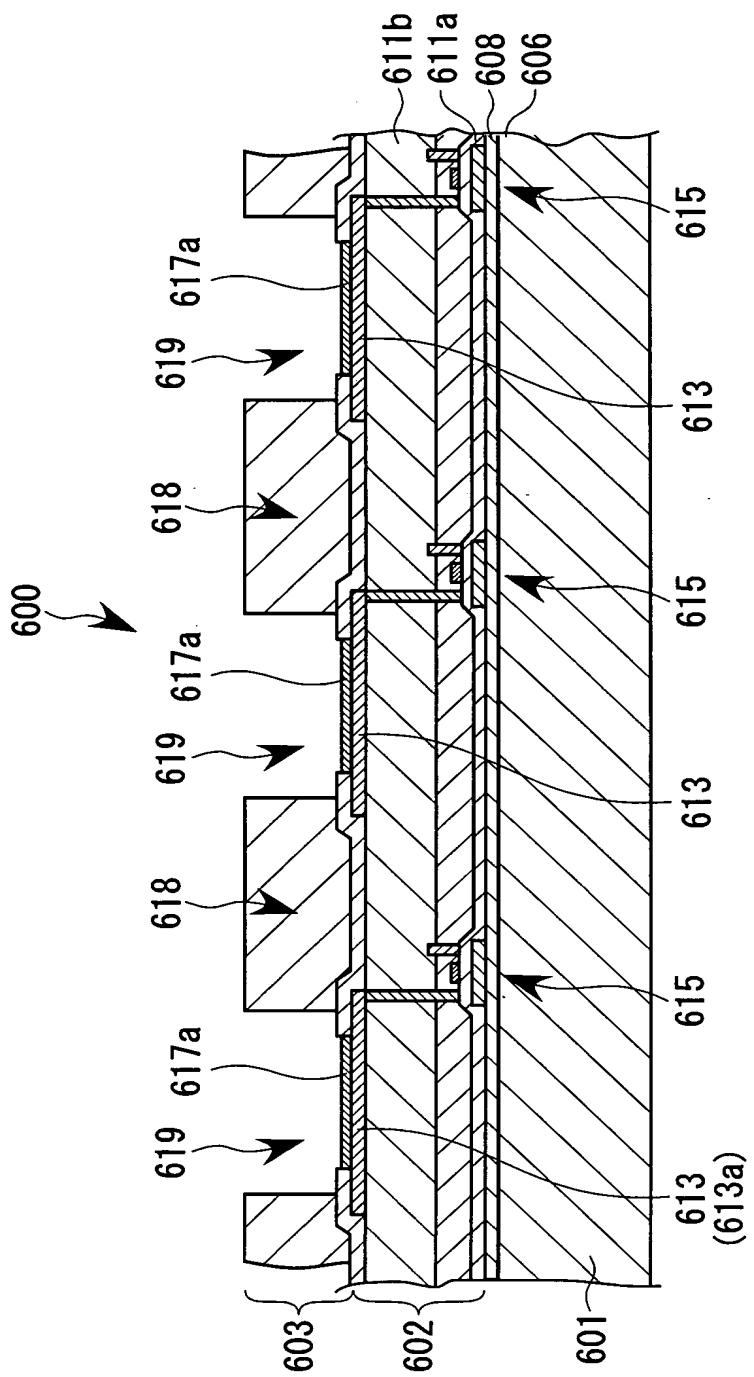


FIG. 27

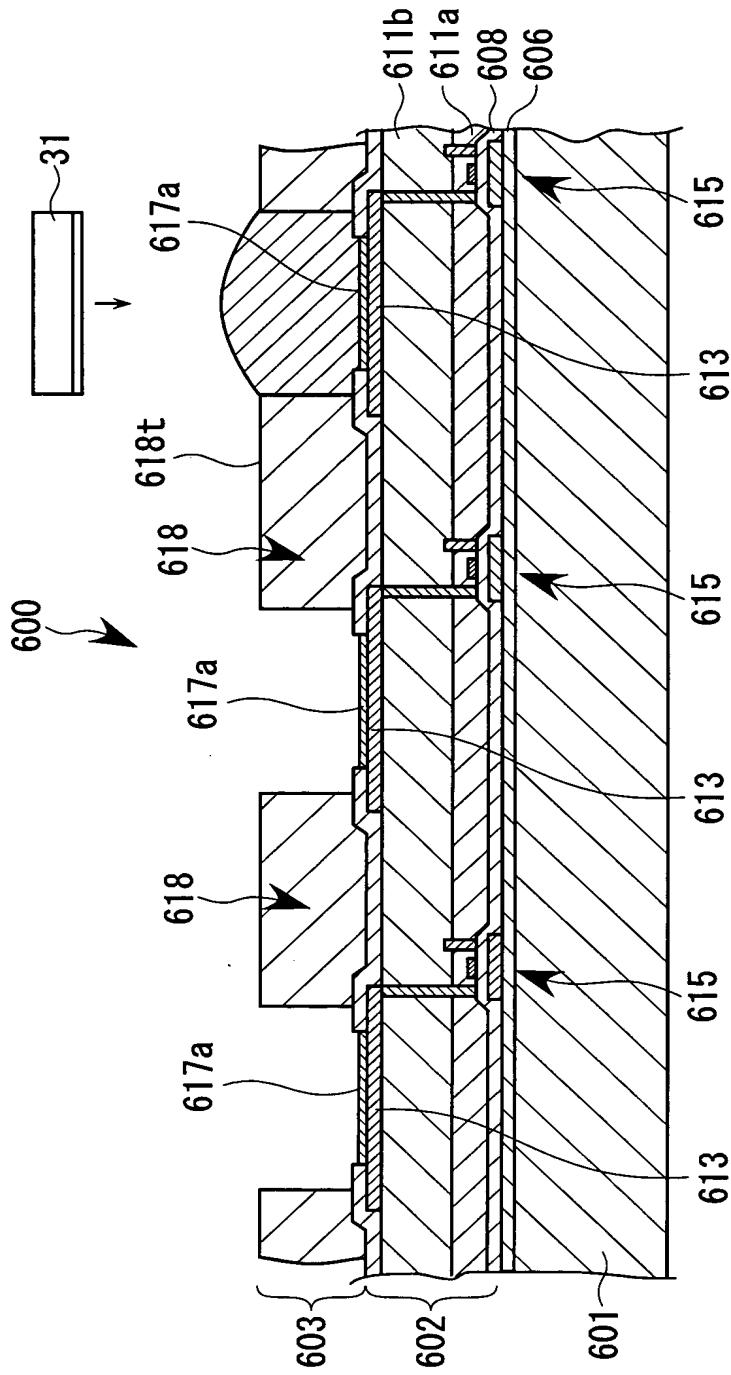


FIG. 28

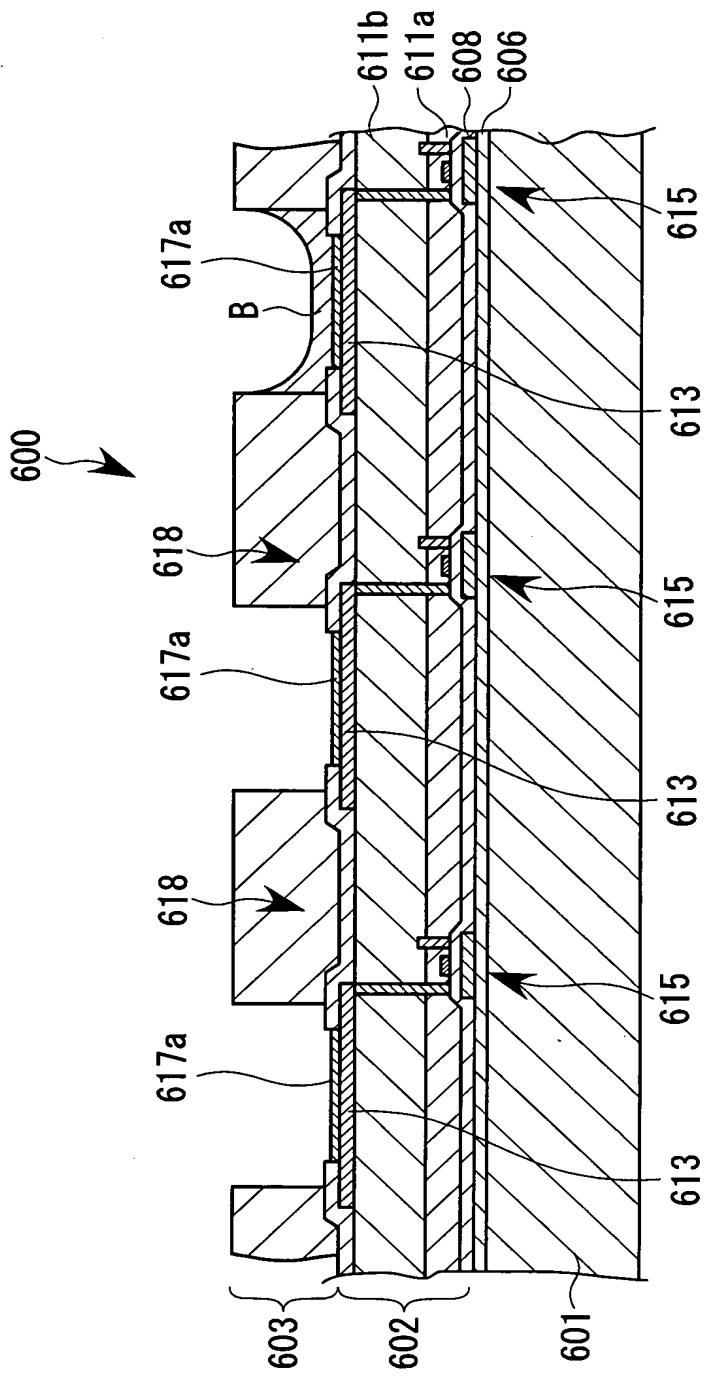


FIG. 29

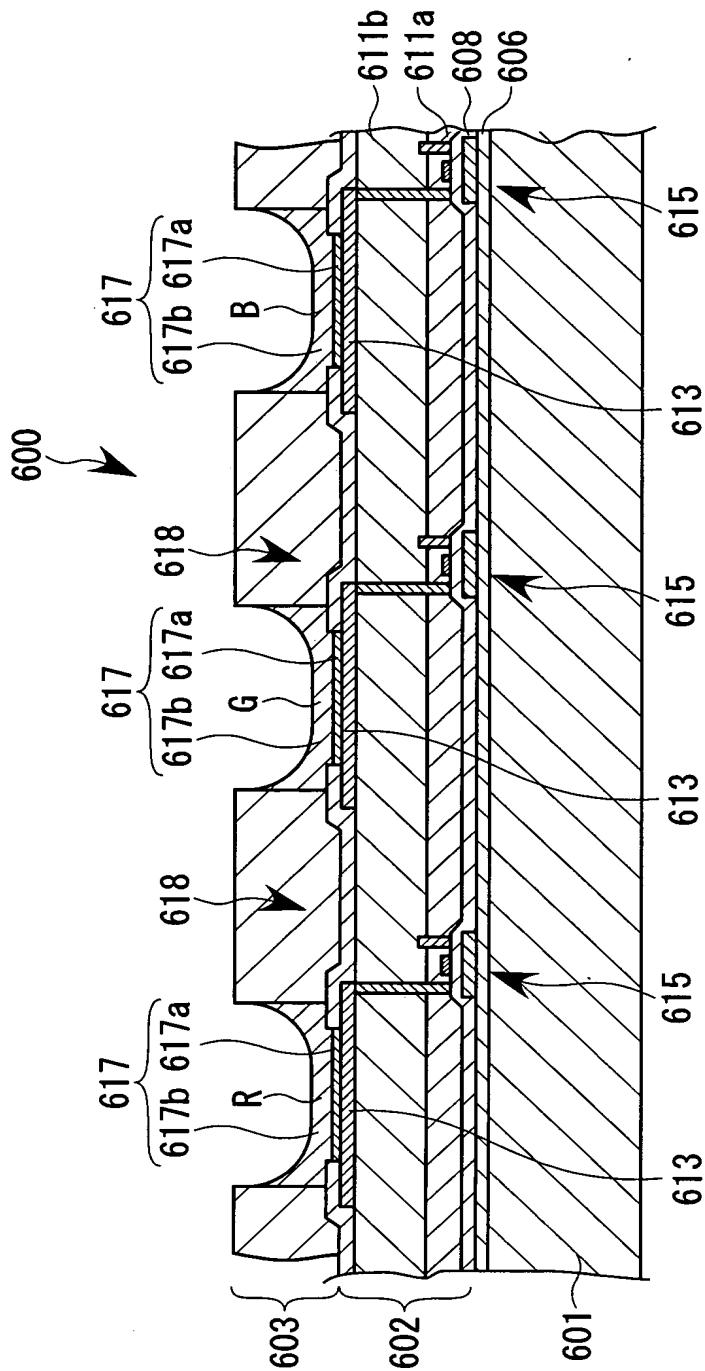
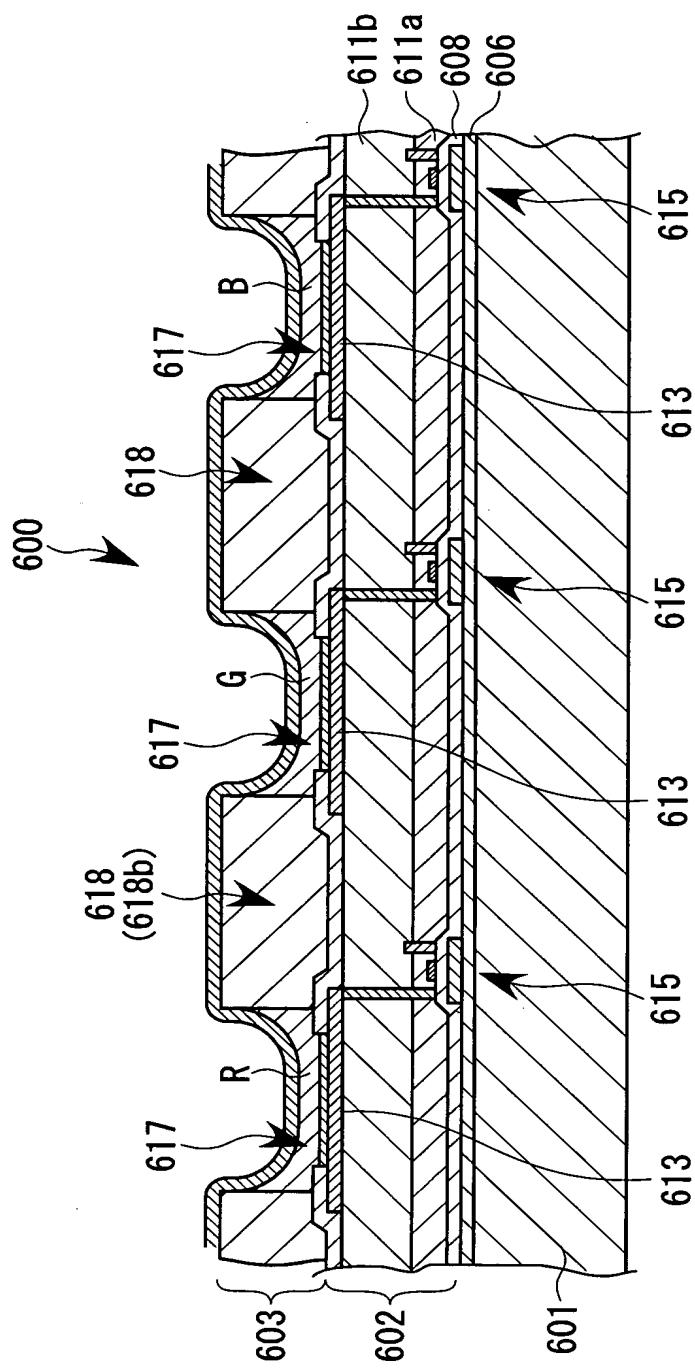


FIG. 30



Title: METHOD OF DETERMINING ABNORMALITY OF NOZZLES IN IMAGING APPARATUS;
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F I G. 3 1

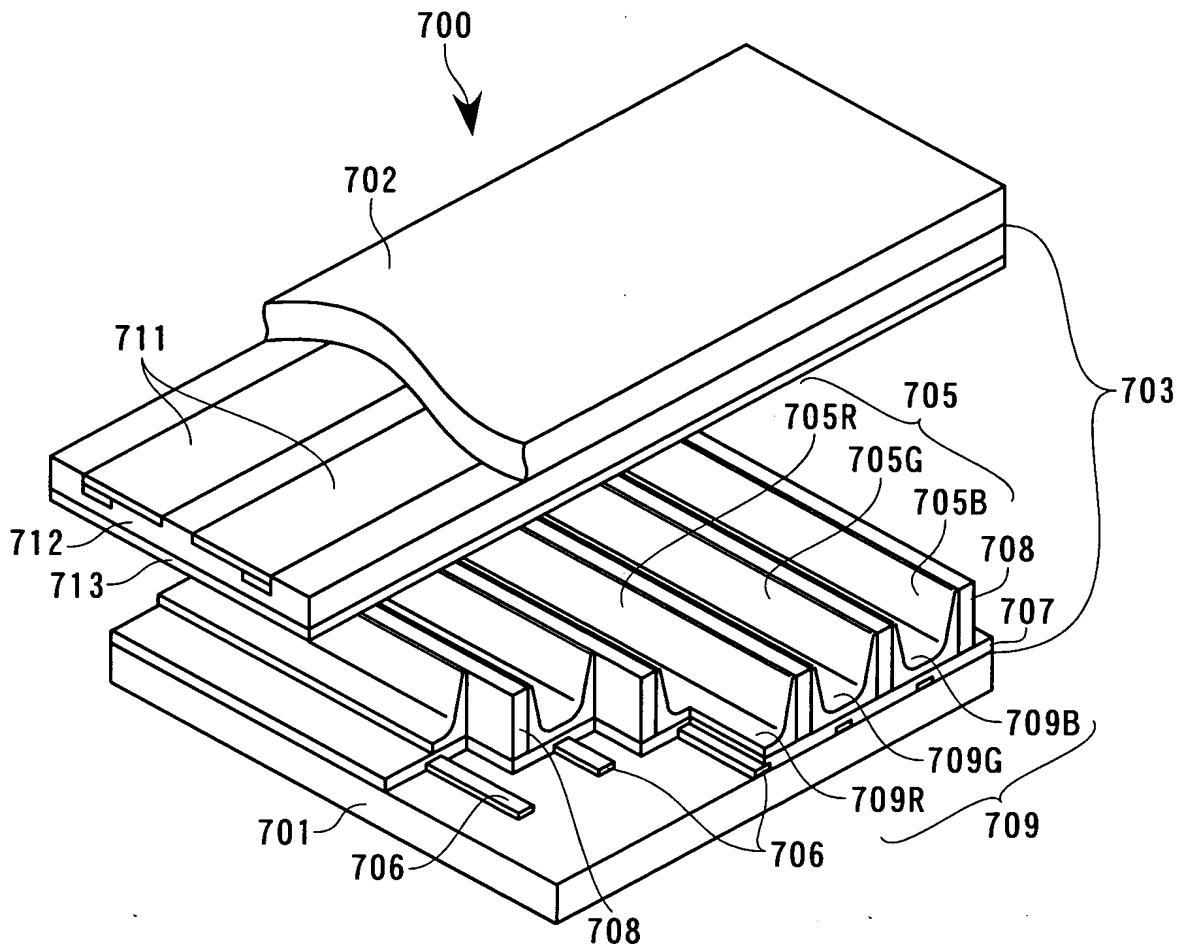
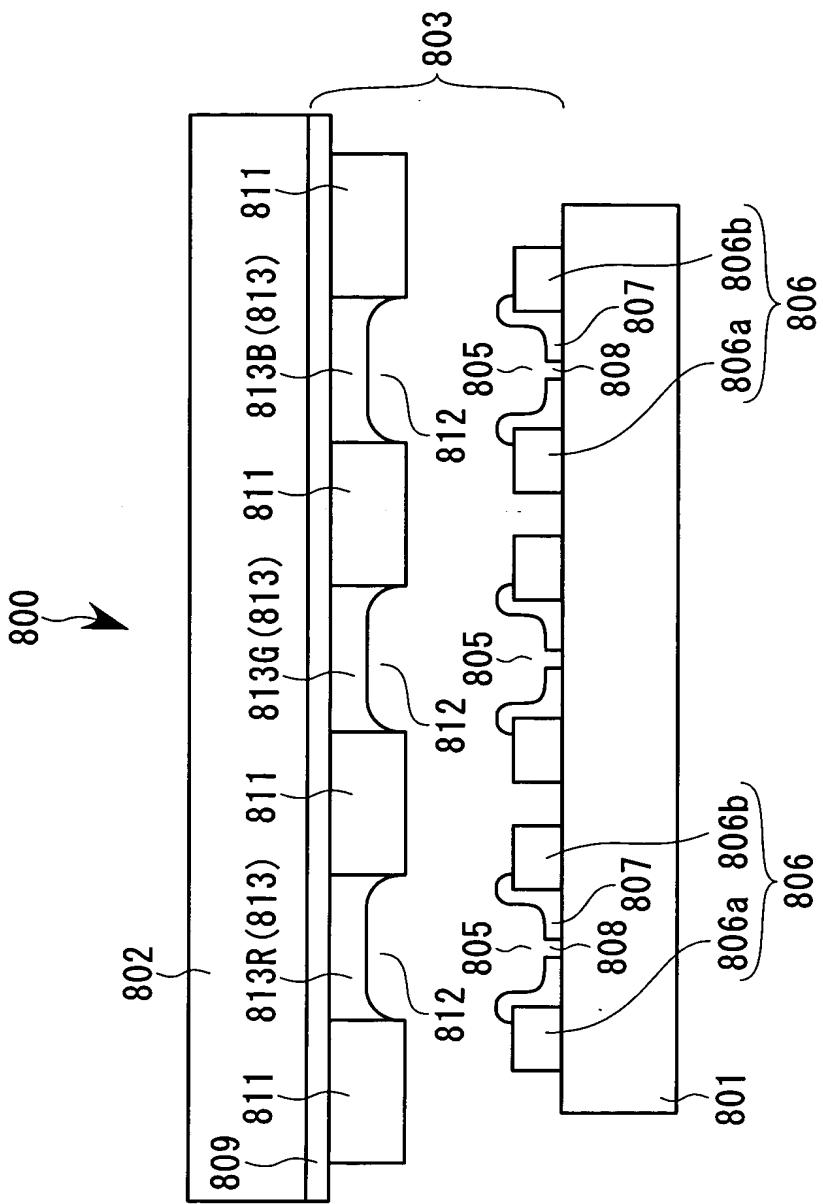


FIG. 32



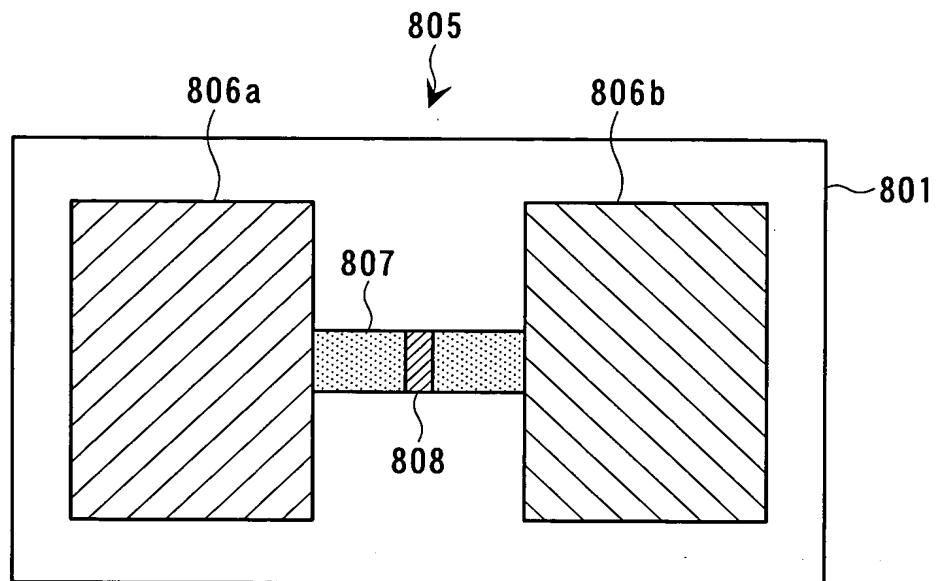
Title: METHOD OF DETERMINING ABNORMALITY OF NOZZLES IN IMAGING APPARATUS;
IMAGING APPARATUS; ELECTROOPTIC DEVICE; METHOD OF MANUFACTURING
ELECTROOPTIC DEVICE; AND ELECTRONIC EQUIPMENT

Inventor: Shinichi NAKAMURA

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F I G. 33 A



F I G. 33 B

